

## Nanotechnology Platform

### User Linked to a Customer Registration Request

**USER INFORMATION\*:**

**USER Nº:**

**COSTUMER Nº:**

\* Person linked to a customer who will assume the cost resulting from the provision of services done at the Platform.

<b>Customer Name and Surname:</b>	
<b>Institution or Company:</b>	
<b>Department / Laboratory:</b>	
<b>User Name and Surname:</b>	
<b>ID Card:</b>	
<b>PCB card number (only for PCB users):</b>	
<b>Job Position:</b>	
<b>Phone Number:</b>	
<b>E-mail:</b>	

**Date, Customer Signature and Institution Stamp:**

#### TERMS AND CONDITIONS:

**Signing this document implies that:**

1. - The user has read the documentation related to the rules and conditions of use of the Nanotechnology Platform.  
<http://www.ibecbarcelona.eu/services/nanotechnology-platform/>
2. - The user must cite the Nanotechnology Platform in publications arising from the service provided.

3. - IBEC is not responsible for property and/or personal damage arising from misuse of facilities and/or violation of safety rules and emergency plan of the building.

4. - Violation of these rules will result in the loss of rights of use of the equipment and facilities of the Nanotechnology Platform.

In compliance with Law 15/1999 of December 13, Protection of Personal Data (LOPD), we inform you that the personal data provided voluntarily in this form will be added and/or updated in a file owned by Foundation Institute for Bioengineering of Catalonia (IBEC), established in C/ Baldiri Reixac, 10-12, 08028 Barcelona aimed to manage service delivery, training and dissemination seminars. At any moment, you may exercise your rights of access, rectification, cancellation and opposition by sending an email to the address [arco@ibecbarcelona.eu](mailto:arco@ibecbarcelona.eu).

I consent to receive by email scientific and technical information as well as information about courses or seminars organized by IBEC. **YES NO**

**Select the equipment/facilities to be used:**

Ultra-High Resolution Field Emission Scanning Electron Microscopy (SEM)	
E-beam Lithography (EBL)	
UV-Photolithography - Mask-aligner	
Direct Write Laser Lithography	
Thermal and E-beam metal evaporator	
Inteferometer	
Profilometer	
Chemical Bath	
Spinner	
Plasma Cleaner	
Optical microscope	
Oven	
UV Curing Lamp System	
Microarrayer	
Contact angle	
Clean Room	